PROCEEDINGS OF SPIE

Gallium Nitride Materials and Devices V

Jen-Inn Chyi Yasushi Nanishi Hadis Morkoç Cole W. Litton Joachim Piprek Euijoon Yoon Editors

25–28 January 2010 San Francisco, California, United States

Sponsored and Published by SPIE

Volume 7602

Proceedings of SPIE, 0277-786X, v. 7602

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

The papers included in this volume were part of the technical conference cited on the cover and title page. Papers were selected and subject to review by the editors and conference program committee. Some conference presentations may not be available for publication. The papers published in these proceedings reflect the work and thoughts of the authors and are published herein as submitted. The publisher is not responsible for the validity of the information or for any outcomes resulting from reliance thereon.

Please use the following format to cite material from this book:

Author(s), "Title of Paper," in *Gallium Nitride Materials and Devices V*, edited by Jen-Inn Chyi, Yasushi Nanishi, Hadis Morkoç, Cole W. Litton, Joachim Piprek, Euijoon Yoon, Proceedings of SPIE Vol. 7602 (SPIE, Bellingham, WA, 2010) Article CID Number.

ISSN 0277-786X ISBN 9780819479983

Published by **SPIE** P.O. Box 10, Bellingham, Washington 98227-0010 USA Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445 SPIE.org

Copyright © 2010, Society of Photo-Optical Instrumentation Engineers

Copying of material in this book for internal or personal use, or for the internal or personal use of specific clients, beyond the fair use provisions granted by the U.S. Copyright Law is authorized by SPIE subject to payment of copying fees. The Transactional Reporting Service base fee for this volume is \$18.00 per article (or portion thereof), which should be paid directly to the Copyright Clearance Center (CCC), 222 Rosewood Drive, Danvers, MA 01923. Payment may also be made electronically through CCC Online at copyright.com. Other copying for republication, resale, advertising or promotion, or any form of systematic or multiple reproduction of any material in this book is prohibited except with permission in writing from the publisher. The CCC fee code is 0277-786X/10/\$18.00.

Printed in the United States of America.

Publication of record for individual papers is online in the SPIE Digital Library.



SPIEDigitalLibrary.org

Paper Numbering: Proceedings of SPIE follow an e-First publication model, with papers published first online and then in print and on CD-ROM. Papers are published as they are submitted and meet publication criteria. A unique, consistent, permanent citation identifier (CID) number is assigned to each article at the time of the first publication. Utilization of CIDs allows articles to be fully citable as soon they are published online, and connects the same identifier to all online, print, and electronic versions of the publication. SPIE uses a six-digit CID article numbering system in which:

- The first four digits correspond to the SPIE volume number.
- The last two digits indicate publication order within the volume using a Base 36 numbering system employing both numerals and letters. These two-number sets start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B ... 0Z, followed by 10-1Z, 20-2Z, etc.

The CID number appears on each page of the manuscript. The complete citation is used on the first page, and an abbreviated version on subsequent pages. Numbers in the index correspond to the last two digits of the six-digit CID number.

Contents

- ix Conference Committee
- xi Dedication to Dr. Cole W. Litton
- xiii Introduction

GROWTH I

- Growth of self-standing GaN substrates (Invited Paper) [7602-01]
 H.-J. Lee, K. Fujii, T. Goto, Tohoku Univ. (Japan); C. Kim, Kyunghee Univ. (Korea, Republic of);
 J. Chang, Korea Maritime Univ. (Korea, Republic of); S.-K. Hong, Chungnam National Univ. (Korea, Republic of); M. Cho, Wavesquare Inc. (Korea, Republic of); T. Yao, Tohoku Univ. (Japan)
- 7602 03 Selective growth and impurity incorporation in semipolar GaN grown on Si substrate (Invited Paper) [7602-02]
 N. Sawaki, Aichi Institute of Technology (Japan) and Nagoya Industrial Science Research Institute (Japan); Y. Honda, T. Hikosaka, S. Tanaka, M. Yamaguchi, N. Koide, K. Tomita, Nagoya Univ. (Japan)

GROWTH II

- 7602 0A Molecular beam epitaxial growth, fabrication, and characterization of InN/Si nanowire heterojunction solar cells [7602-09] Y.-L. Chang, Z. Mi, McGill Univ. (Canada)
- The comprehensive characteristics of quaternary AllnGaN with various TMI molar rate [7602-10]
 S.-F. Yu, S.-J. Chang, S.-P. Chang, National Cheng Kung Univ. (Taiwan); R.-M. Lin, Chang Gung Univ. (Taiwan)

GROWTH III

 7602 0C Ammonothermal growth of GaN substrates (Invited Paper) [7602-11] R. Dwiliński, R. Doradziński, J. Garczyński, L. Sierzputowski, R. Kucharski, M. Zając, Ammono Sp. z o.o. (Poland); M. Rudziński, W. Strupiński, Institute of Electronic Materials Technology (Poland); J. Serafińczuk, R. Kudrawiec, Wroclaw Univ. of Technology (Poland)
 7602 0D Non-polar m-plane GaN film and polarized InGaN/GaN LED grown on LiAlO₂ (001) substrates (Invited Paper) [7602-12] R. Zhang, Z. L. Xie, B. Liu, X. Q. Xiu, D. Y. Fu, Z. Zhang, P. Han, Y. D. Zheng, Nanjing Univ. (China); S. M. Zhou, Shanghai Institute of Optics and Fine Mechanics (China)
 7602 0E Magnetic cages of GaN nanoclusters doped with Gd and Nd [7602-13] V. Kumar, Dr. Vijay Kumar Foundation (India); J. M. Zavada, U.S. Army Research Office (United States)

7602 0G	Extended defects in semipolar (11-22) gallium nitride [7602-15]
	Y. Arroyo-Rojas Dasilva, P. Ruterana, CIMAP, CNRS-ENSICAEN-CEA-UCBN (France);
	L. Lahourcade, E. Monroy, INAC/SP2M/PSC (France); G. Nataf, CRHEA, CNRS (France)

FETS

7602 OH	Plasmon-assisted dissipation of LO-mode heat in nitride 2DEG channels [7602-16]
	A. Matulionis, J. Liberis, Puslaidininkiu Fizikos Institutas (Lithuania); H. Morkoç, Virginia
	Commonwealth Univ. (United States)

- 7602 0I InGaN light-emitting diodes with highly transparent ZnO:Ga electrodes [7602-79]
 H. Y. Liu, X. Li, X. Ni, V. Avrutin, N. Izyumskaya, Ü. Özgür, H. Morkoç, Virginia Commonwealth Univ. (United States)
- 7602 0K Transmission electron microscopy and XRD investigations of InAIN/GaN thin heterostructures for HEMT applications [7602-19]
 A. Vilalta-Clemente, M. Morales, M. P. Chauvat, Y. Arroyo-Rojas Dasilva, CIMAP, CNRS-ENSICAEN-CEA-UCBN (France); M. A. Poisson, Alcatel-Thales III-V Lab. (France); M. Heuken, C. Giesen, AIXTRON AG (Germany); P. Ruterana, CIMAP, CNRS-ENSICAEN-CEA-UCBN (France)

FET RELIABILTY

- 7602 OL Quantum 1/f noise theory and experiment in QWIPs [7602-20] A. M. Truong, P. H. Handel, Univ. of Missouri-St. Louis (United States)
- 7602 0M
 1/f noise: a window to HFET stability [7602-21]
 P. H. Handel, T. Sherif, Univ. of Missouri-St. Louis (United States); C. Kayis, J. Leach, C. Zhu, H. Morkoç, Virginia Commonwealth Univ. (United States)
- 7602 0N Analytical calculation of the quantum 1/f coherence parameter for HFETs [7602-22] P. H. Handel, T. S. Sherif, Univ. of Missouri-St. Louis (United States)
- 7602 00 Measurements of gate lag in high-quality nearly lattice matched InAIN/AIN/GaN HFET structures [7602-23]
 J. H. Leach, M. Wu, X. Ni, X. Li, Ü. Özgür, H. Morkoç, Virginia Commonwealth Univ. (United States)

ADVANCED TECHNIQUES I

- Nano-ultrasonic based on GaN nano-layers (Invited Paper) [7602-25]
 C.-K. Sun, National Taiwan Univ. (Taiwan) and Research Ctr. for Applied Sciences (Taiwan);
 Y.-C. Wen, Y.-H. Chen, National Taiwan Univ. (Taiwan); K.-H. Lin, Industrial Technology
 Research Institute South (Taiwan)
- 7602 0T Scanning near-field optical spectroscopy of AlGaN-based light emitting diodes [7602-28] A. Pinos, S. Marcinkevičius, Royal Institute of Technology (Sweden)

Thermal conductivity measurement of pulsed-MOVPE InN alloy grown on GaN/Sapphire by 3ω method [7602-29]
 H. Tong, J. Zhang, H. Zhao, G. Liu, V. A. Handara, J. A. Herbsommer, N. Tansu, Lehigh Univ. (United States)

ADVANCED TECHNIQUES II

- Fifect of UV exposure on the surface charge behavior for GaN [7602-33]
 M. Foussekis, J. D. Ferguson, X. Ni, H. Morkoç, M. A. Reshchikov, A. A. Baski, Virginia Commonwealth Univ. (United States)
- Achieving p-In_xGa_{1-x}N alloys with high In contents [7602-34]
 B. N. Pantha, A. Sedhain, J. Li, J. Y. Lin, H. X. Jiang, Texas Tech Univ. (United States)

QW AND DOTS

 7602 12 Extended defects in nitride layers, influence on the quantum wells and quantum dots (Invited Paper) [7602-37]
 P. Ruterana, M. P. Chauvat, Y. Arroyo Rojas Dasilva, H. Lei, CIMAP, CNRS-ENSICAEN-CEA-UCBN (France); L. Lahourcade, E. Monroy, INAC/SP2M/PSC (France)

LASERS

- The lasing characteristics of GaN-based two-dimensional photonic crystal surface-emitting lasers (Invited Paper) [7602-40]
 S. W. Chen, T. T. Kao, T. T. Wu, T. C. Lu, H. C. Kuo, S. C. Wang, National Chiao Tung Univ. (Taiwan)
- 7602 17 GaN-based VCSELs: analysis of internal device physics and performance limitations [7602-42]

J. Piprek, NUSOD Institute LLC (United States); S. Li, Crosslight Software Inc. (Canada)

High-power high-efficiency continuous-wave InGaN laser diodes in the violet, blue, and green wavelength regimes [7602-43]
 J. W. Raring, E. M. Hall, M. C. Schmidt, C. Poblenz, B. Li, N. Pfister, D. F. Feezell, R. Craig,

J. S. Speck, S. P. DenBaars, S. Nakamura, Kaai, Inc. (United States)

Performance improvement of InGaN-based laser diodes by epitaxial layer structure design [7602-44]
 J. Liu, Y. Zhang, Z. Lochner, S.-S. Kim, Georgia Institute of Technology (United States); H. Kim, Chonbuk National Univ. (Korea, Republic of); J.-H. Ryou, S.-C. Shen, P. D. Yoder, R. D. Dupuis, Georgia Institute of Technology (United States); Q. Wei, K. Sun, A. Fischer, F. Ponce, Arizona State Univ. (United States)

NOVEL DEVICES

- 7602 1A Review of nitride infrared intersubband devices (Invited Paper) [7602-45]
 M. Tchernycheva, F. H. Julien, Institut d'Electronique Fondamentale, CNRS, Univ. Paris-Sud 11 (France); E. Monroy, Commissariat à l'Énergie Atomique (France)
- First-principles simulation of GaN material and devices: an application to GaN APDs (Invited Paper) [7602-46]
 E. Bellotti, M. Moresco, Boston Univ. (United States); F. Bertazzi, Boston Univ. (United States) and Politecnico di Torino (Italy)

7602 1E Promising composite die-bonding materials for high-power GaN-based LED applications

[7602-50] R.-H. Horng, National Cheng Kung Univ. (Taiwan); J.-S. Hong, Y.-L. Tsai, C.-J. Chen, C.-M. Chen, D.-S. Wuu, National Chung Hsing Univ. (Taiwan)

LEDS I

7602 1F Realization of high-efficiency AlGaN-based ultraviolet light emitters (Invited Paper) [7602-51]

S.-R.Jeon, S.-J. Lee, I.-K. Kang, J. B. Kim, N. Hwang, Korea Photonics Technology Institute (Korea, Republic of); S.-J. Son, LG Innotek (Korea, Republic of)

7602 1G Novel device concepts for high-efficiency InGaN-based light-emitting diodes (Invited Paper) [7602-52]
 H. Zhao, G. Liu, Y.-K. Ee, X.-H. Li, H. Tong, J. Zhang, G. S. Huang, N. Tansu, Lehigh Univ. (United

H. Zhao, G. Liu, Y.-K. Ee, X.-H. Li, H. Tong, J. Zhang, G. S. Huang, N. Tansu, Lenigh Univ. (United States)

 Role of interface roughness on lateral transport in InGaN/GaN LEDs: diffusion length, dislocation spacing, and radiative efficiency [7602-53]
 I.-L. Lu, Y.-R. Wu, National Taiwan Univ. (Taiwan); J. M. Hinckley, J. Singh, Univ. of Michigan (United States)

LEDS II

- Development of high-power UV LEDs for epoxy curing applications (Invited Paper) [7602-56]
 W. H. Liu, C. F. Chu, C. C. Cheng, K. H. Hsu, Y. T. Chung, Y. K. Wang, C. C. Li, J. Y. Chu,
 F. H. Fan, H. C. Cheng, Y. W. Chen, Y. H. Chang, L. W. Shan, SemiLEDs Optoelectronics Corp. (Taiwan); T. Doan, C. Tran, SemiLEDs Corp. (United States)
- 7602 1L Original GaN-based LED structure on ZnO template by MOCVD [7602-57]
 R.-M. Lin, National Cheng Kung Univ. (Taiwan); S.-F. Yu, Chang Gung Univ. (Taiwan);
 M.-J. Chen, National Taiwan Univ. (Taiwan); W.-C. Hsu, Sino-American Silicon Products Inc. (Taiwan)
- The structure [7602-58]
 T. Kondo, A. Suzuki, F. Teramae, T. Kitano, Y. Kaneko, EL-SEED Corp. (Japan); R. Kawai,

K. Teshima, S. Maeda, Meijo Univ. (Japan); S. Kamiyama, Meijo Univ. (Japan) and EL-SEED Corp. (Japan); M. Iwaya, H. Amano, I. Akasaki, Meijo Univ. (Japan) 7602 1N Internal quantum efficiency of m-plane InGaN on Si and GaN [7602-59]
 J. Lee, X. Ni, M. Wu, X. Li, R. Shimada, Ü. Özgür, A. A. Baski, H. Morkoç, Virginia Commonwealth Univ. (United States); T. Paskova, G. Mulholland, K. R. Evans, Kyma Technologies, Inc. (United States)

LEDS III

7602 1R Efficiency retention at high current injection levels in *m*-plane InGaN light emitting diodes
 [7602-63]
 X. Li, X. Ni, J. Lee, M. Wu, Ü. Özgür, H. Morkoç, Virginia Commonwealth Univ. (United States);

T. Paskova, G. Mulholland, K. R. Evans, Kyma Technologies, Inc. (United States)

POSTER SESSION

Ab initio study of structural properties for zincblende AllnN: comparison of LDA and GGA [7602-68]
 B.-T. Liou, Hsiuping Institute of Technology (Taiwan); B.-Y. Wu, De-Lin Institute of Technology

(Taiwan)

- 7602 1X Output power enhancement of light-emitting diodes with defect passivation layer [7602-69]
 M.-H. Lo, P.-M. Tu, National Chiao Tung Univ. (Taiwan); Y.-J. Cheng, National Chiao Tung Univ. (Taiwan) and Research Ctr. for Applied Sciences, Academia Sinica (Taiwan);
 C.-H. Wang, C.-W. Hung, National Chiao Tung Univ. (Taiwan); S.-C. Hsu, Tamkang Univ. (Taiwan); H.-C. Kuo, H.-W. Zan, S.-C. Wang, C.-Y. Chang, National Chiao Tung Univ. (Taiwan);
 C.-M. Liu, Sino-American Silicon Products Inc. (Taiwan)
- Non-polar m-plane GaN on patterned Si(112) substrates by metalorganic chemical vapor deposition [7602-73]
 X. Ni, M. Wu, J. Lee, X. Li, A. Baski, Ü. Özgür, H. Morkoç, Virginia Commonwealth Univ. (United States)
- Comparison of different template structures for high quality and self-separation thick GaN growth [7602-74]
 Y.-H. Fang, C.-L. Chao, T.-W. Chi, K.-M. Chen, P.-C. Liu, J.-D. Tsay, Industrial Technology Research Institute (Taiwan)
- 7602 22 Analytical methods to study loss mechanisms and lifetime investigations of blue InGaN laser diodes [7602-75]

J. Müller, G. Brüderl, M. Schillgalies, A. Breidenassel, S. Tautz, D. Dini, T. Lermer, S. Lutgen, U. Strauß, OSRAM Opto Semiconductors GmbH (Germany)

- 7602 23 Reduction in operating voltage of UV laser diode [7602-76]
 T. Ichikawa, K. Takeda, Y. Ogiso, K. Nagata, M. Iwaya, S. Kamiyama, H. Amano, I. Akasaki, Meijo Univ. (Japan); H. Yoshida, M. Kuwabara, Y. Yamashita, H. Kan, Hamamatsu Photonics K.K. (Japan)
- 7602 24 On carrier spillover in c- and m-plane InGaN light-emitting diodes [7602-77]
 J. Lee, X. Li, X. Ni, Ü. Özgür, H. Morkoç, Virginia Commonwealth Univ. (United States);
 T. Paskova, G. Mulholland, K. R. Evans, Kyma Technologies, Inc. (United States)

7602 25 Analysis and comparison of UV photodetectors based on wide bandgap semiconductors [7602-78]

Q. Wang, S. Savage, B. Noharet, I. Petermann, S. Persson, S. Almqvist, M. Bakowski, J. Y. Andersson, Acreo AB (Sweden) and IMAGIC Ctr. (Sweden)

Author Index

Conference Committee

Symposium Chair

E. Fred Schubert, Rensselaer Polytechnic Institute (United States)

Symposium Cochairs

Liang-Chy Chien, Kent State University (United States) James G. Grote, Air Force Research Laboratory (United States)

Program Track Chair

James G. Grote, Air Force Research Laboratory (United States)

Conference Chairs

Jen-Inn Chyi, National Central University (Taiwan) Yasushi Nanishi, Ritsumeikan University (Japan) Hadis Morkoç, Virginia Commonwealth University (United States)

Conference Cochairs

Cole W. Litton, Air Force Research Laboratory - retired (United States) **Joachim Piprek**, NUSOD Institute LLC (United States) **Euijoon Yoon**, Seoul National University (Korea, Republic of)

Program Committee

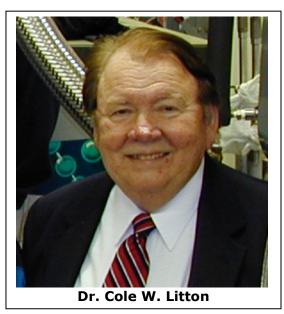
Hiroshi Amano, Meijo University (Japan) Alison A. Baski, Virginia Commonwealth University (United States) Tzer-Perng Chen, Epistar Corporation (Taiwan) Hiroshi Fujioka, The University of Tokyo (Japan) Nicolas Grandjean, Ecole Polytechnique Fédérale de Lausanne (Switzerland) Shangir Gwo, National Tsing Hua University (Taiwan) Toshihide Kikkawa, Fujitsu Company (Japan) Katsumi Kishino, Sophia University (Japan) Hao-Chung Kuo, National Chiao Tung University (Taiwan) Narihiko Maeda, NTT Photonics Laboratories (Japan) Hideto Miyake, Mie University (Japan) Yong-Tae Moon, LG Electronics Inc. (Korea, Republic of) Takashi Mukai, Nichia Corporation (Japan) Ok-Hyun Nam, Korea Polytechnic University (Korea, Republic of) Kitt C. Reinhardt, Air Force Office of Scientific Research (United States) Donald J. Silversmith, Air Force Office of Scientific Research (United States) Cheolsoo Sone, Samsung Electro-Mechanics (Korea, Republic of)

Chih-Chung Yang, National Taiwan University (Taiwan)

Session Chairs

- Growth I
 Hadis Morkoç, Virginia Commonwealth University (United States)
- 2 Growth II Alois J. Krost, Otto-von-Guericke-Universität Magdeburg (Germany)
- 3 Growth III Cole W. Litton, Air Force Research Laboratory - retired (United States)
- 4 FETs Peter H. Handel, University of Missouri-St. Louis (United States)
- 5 FET Reliabilty Yasushi Nanishi, Ritsumeikan University (Japan)
- Advanced Techniques I
 Shigefusa F. Chichibu, Tohoku University (Japan)
- 7 Advanced Techniques II
 Russell D. Dupuis, Georgia Institute of Technology (United States)
- 8 QW and Dots Sandra Ruffenach, Université Montpellier 2 (France)
- Lasers
 Dong-Seon Lee, Gwangju Institute of Science and Technology (Korea, Republic of)
- 10 Novel Devices Joachim Piprek, NUSOD Institute LLC (United States)
- Poster Highlight
 Hadis Morkoç, Virginia Commonwealth University (United States)
- 12 LEDs I Avery Liu, SemiLEDs Corporation (United States)
- 13 LEDs II Ferdinand Scholz, Universität Ulm (Germany)
- 14 LEDs III **Hideto Miyake**, Mie University (Japan)
- 15 LEDs IV Jen-Inn Chyi, National Central University (Taiwan)

Dedication



It is with great honor and the deepest sadness that we dedicate these proceedings to the memory of Cole W. Litton who passed away while attending the conference on January 26, 2010, shortly after the completion of the last session that day. He cherished every aspect of organizing the conference and if he were to use a narrative for his passing it might not have been much different from what actually took place. The solace that we can all draw from this, if there is one, is that he passed on while doing what he loved most.

Dr. Litton started the series on Gallium Nitride Materials and

Devices in 1996 and took care of all that had to be done on his own as his cochair that year, Hadis Morkoç, was involuntarily committed to a myriad of other must do duties and could not be of much help. It is worth noting that the proceedings of the first Gallium Nitride Materials and Devices series was dedicated to commemorate the occasion of the retirement of his and our long time colleague Dr. G. L. Witt after many decades of service to the research community. Cole had dedicated himself to research and development as researcher and program manager, and also to his colleagues for many decades, in particular to his younger colleagues as they navigated through the complex web of science and engineering.

On the personal side, he was a kind and caring individual who never seemed to lose his composure under any circumstances. He will surely be missed by many whom he directly and indirectly touched, and will be affected by the absence of calming presence and guidance.

Introduction

GaN based electronic and optoelectronic devices continue to develop rapidly as reflected by the advances reported at the meeting. Today, the GaN based light emitters adorn the automobiles, traffic lights, moving signs, outdoor displays, handheld electronics, and background lighting in many consumer electronics including flat panel televisions. All LED outdoor lighting applications are already in full swing. Indoor lighting with LEDs seems to be the frontier that GaN seems surely conquering with all manufacturers being under capacity due to increasing demand. The wall-plug efficiencies in excess of 50% at brightness levels needed for lighting certainly bode well for GaN based LEDs. Efficiency retention or the loss of it at high injection levels has received a great deal of attention due to the enormous impact of efficiency on indoor lighting by LEDs. To the end, non polar and semi-polar orientations of GaN and InGaN in the context of growth and investigations of optical processes are in full swing. Due to cost pressures, Si substrates for GaN epitaxy with clever patterning and strain balancing, to avoid cracking upon cooling from growth temperatures, being implemented. Measurement of internal quantum efficiency has been recognized to be an important step in the LED development for many years and the issue has come to the forefront in relation to GaN based LEDs as indicated by presentations and discussions on the topic.

The last year's program featured a good deal of shorter wavelength LEDs for medical applications, skin ailment treatment, curing of polymers, and applications such as water purification as well as short range communication are also being developed. The conference this year was representative of this push, but also a push for longer wavelengths for lasers as well as LEDs. The latter application is in part driven by lighting applications in case the tri-color approach, using red, green and blue LEDs, is used for general lighting applications.

Switching gears to FETs, the last year's program had a good deal of focus on both high power RF and switching applications of GaN based FETs and other three terminal devices. This year the focus centered on the carrier transport and the associated scattering mechanisms, the routes for heat dissipation from hot electrons to the heat sink. It was reported that the enhanced coupling of hot electrons with LO phonons and inability in general for LO phonons to LA phonons lead to high density of hot phonons with equivalent temperatures in the range of 2000 K, much like the hot electrons. With participation of plasmons, particularly at carrier densities corresponding to the plasma frequency that is resonant with GaN LO phonon energy efficient decay of LO phonons was noted and used to enhance carrier velocity and also improve reliability of FETs. Also introduced was the use of low frequency noise measurement to measure the degree of degradation in FETs. These measurements were noted to be much more sensitive to degradation as compared to e.g. I-V measurements. Many devices, particularly FETs, are sensitive to surfaces and their preparation. Surface charge sensitive probes used to view not only the surface of GaN but also its evolution when subjected to various ambient conditions.

The SPIE symposium on GaN Materials and Devices is annually organized to disseminate the latest results and provide an opportunity for researchers from around the world to engage in far reaching and probing discussions. Many world renowned invited speakers from Asia, Europe and USA set the stage with wide ranging formal discussions. Not to be underestimated is the fact that the meeting served the purpose of getting experts and newcomers together for friendship and informal discussions of issues relevant to GaN and related materials and devices, and also to develop collaborations. Such exchanges will undoubtedly play an invaluable role in the propelling the field forward in general and in particular addressing pivotal issues such as determination and improvement of internal quantum efficiency in GaN and related materials and external quantum efficiency.

> Cole W. Litton (deceased) Jen-Inn Chyi Yasushi Nanishi Hadis Morkoç Joachim Piprek Euijoon Yoon